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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
PATENT EXAMINING OPERATION

Applicant(s): Philippe STAIB

Serial No: 10/664,718

Group Art Unit: 2881

Filed: September 17, 2003

Examiner: Bernard E. Souw

Att. Docket No.: B1180/20019

Confirmation No.: 4374

For: ELECTRON DIFFRACTION SYSTEM FOR USE IN PRODUCTION
ENVIRONMENT AND FOR HIGH PRESSURE DEPOSITION TECHNIQUESAMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

INTRODUCTORY COMMENTS

In response to the Office Action dated May 6, 2004, the time for responding thereto being extended in accordance with a Petition for Extension of Time submitted herewith, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.